

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Toshiji TAIJI et al.

Conf. 2404

Application No. 10/616,914

Group 1765

Filed July 11, 2003

Examiner L. Umez Eronini

SLURRY FOR CHEMICAL MECHANICAL POLISHING

AMENDMENT

Assistant Commissioner for Patents October 21, 2005 P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Official Action mailed June 2, 2005, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 4 of this paper.